

# Mohammad Mahdavi

## List of Publications by Year in descending order

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Version: 2024-02-01

20  
papers

131  
citations

1307594

7  
h-index

1474206

9  
g-index

20  
all docs

20  
docs citations

20  
times ranked

129  
citing authors

#	ARTICLE	IF	CITATIONS
1	Nanoelectromechanical resonant narrow-band amplifiers. <i>Microsystems and Nanoengineering</i> , 2016, 2, 16004.	7.0	25
2	High Dynamic Range AFM Cantilever With a Collocated Piezoelectric Actuator-Sensor Pair. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 260-267.	2.5	13
3	Highly parallel scanning tunneling microscope based hydrogen depassivation lithography. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2018, 36, .	1.2	11
4	Thin Film Piezoelectric-on-Silicon Elliptical Resonators With Low Liquid Phase Motional Resistances. <i>IEEE Sensors Journal</i> , 2019, 19, 113-120.	4.7	9
5	Q Control of an AFM Microcantilever With Double-Stack AlN Sensors and Actuators. <i>IEEE Sensors Journal</i> , 2022, 22, 3957-3964.	4.7	8
6	Piezoelectric resonant MEMS balances with high liquid phase Q. , 2014, , .		7
7	Ultra sensitive lorentz force MEMS magnetometer with pico-tesla limit of detection. , 2015, , .		7
8	AFM Microcantilever With a Collocated AlN Sensor-Actuator Pair: Enabling Efficient Q-Control for Dynamic Imaging. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 661-668.	2.5	7
9	Modal Actuation and Sensing With an Active AFM Cantilever. <i>IEEE Sensors Journal</i> , 2021, 21, 8950-8959.	4.7	7
10	A High Dynamic Range AFM Probe with Collocated Piezoelectric Transducer Pairs. , 2020, , .		6
11	SOI-MEMS Bulk Piezoresistive Displacement Sensor: A Comparative Study of Readout Circuits. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 43-53.	2.5	5
12	High resolution atomic force microscopy with an active piezoelectric microcantilever. <i>Review of Scientific Instruments</i> , 2022, 93, .	1.3	5
13	SNR improvement in amplitude modulated resonant MEMS sensors via thermal-piezoresistive internal amplification. , 2015, , .		4
14	Microresonator-on-Membrane for Real-Time Mass Sensing in Liquid Phase. , 2018, 2, 1-4.		4
15	FPGA-Based Characterization and Q-Control of an Active AFM Cantilever. , 2020, , .		4
16	Nano-precision micromachined frequency output profilometer. , 2016, , .		3
17	Frequency output MEMS resonator on membrane pressure sensors. , 2016, , .		3
18	MEMS resonant sensors for real-time thin film shear stress monitoring. , 2016, , .		3

#	ARTICLE	IF	CITATIONS
19	Micro-Resonator-on-Membrane for Real-Time Biosensing. , 2018, , .		0
20	Active Microcantilevers for Dynamic Mode Atomic Force Microscopy. , 2021, , .		0